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**PATENT**  
**29925/37976**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Application of: Dong-Su Park and Kwang-Seok Jeon

Serial No.: 10/021,322

Filed: December 12, 2001

For: Method for Manufacturing  
Tantalum Oxy Nitride Capacitors

Group Art Unit: 3729

Examiner: Donghai D. Nguyen

I hereby certify that this paper and the documents referred to as enclosed therewith are being deposited with the United States Postal Service as first class mail, postage prepaid, on **August 23, 2004**, in an envelope addressed to Commissioner for Patents, P.O. Box 1450 Alexandria, Virginia 22313-1450

Michael R. Hull  
Reg. No. 55,902  
Attorney for Applicants

## AMENDMENT AFTER FINAL

Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

Dear Commissioner:

Please enter the following amendment in the above-referenced patent application in response to the final Office Action mailed on May 24, 2004.

Amendments to the claims and a complete listing of the claims begins on page 2 of this paper.

Remarks being on page 7 of this paper.

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